

Search Notes

Application No.

10/600,393

Examiner

Toniae M. Thomas

Applicant(s)

CHEN ET AL.

Art Unit

2822

Page 1

| SEARCHED | | | |
|-----------------|-----------|-----------|----------|
| Class | Subclass | Date | Examiner |
| 438 | 275 | 9/10/2004 | TMT |
| " | 770-777 | 9/10/2004 | " |
| " | 787-788 | 9/10/2004 | " |
| " | 791-792 | 9/10/2004 | " |
| 438 | 981 | 9/10/2004 | TMT |
| updated | all above | 3/18/2005 | TMT |
| updated | all above | 7/11/2005 | TMT |
| 438 | 199 | 7/11/2005 | " |
| " | 706 | 7/11/2005 | " |
| " | 710 | 7/11/2005 | " |
| " | 723-724 | 7/11/2005 | " |
| " | 745 | 7/11/2005 | " |
| " | 756-757 | 7/11/2005 | " |
| | | | |

| INTERFERENCE SEARCHED | | | |
|------------------------------|-----------|-----------|----------|
| Class | Subclass | Date | Examiner |
| 438 | all above | 7/11/2005 | TMT |
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| SEARCH NOTES (INCLUDING SEARCH STRATEGY) | | |
|---|-----------|------|
| | DATE | EXMR |
| USPAT US PG-Pub | 9/10/2004 | TMT |
| USPAT US PG-Pub | 9/9/2004 | TMT |
| USPAT US PG-Pub | 9/8/2004 | TMT |
| NPL database (silicon nitride and (atomic layer chemical vapor deposition or atomic layer deposition)) | 9/10/2004 | TMT |
| NPL (silicon nitride and remote plasma enhanced chemical vapor deposition) | 9/10/2004 | TMT |
| none | 7/11/2005 | TMT |
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